

PRESSURE SENSITIVE ELEMENT

Patent Number: JP9213168

Publication date: 1997-08-15

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Requested Patent: JP9213168

Application Number: JP19960040681 19960202

Priority Number(s):

IPC Classification: H01H13/52 ; H01C10/10 ; H01H13/00 ; H01L29/84

EC Classification:

Equivalents: JP3143858B2

Abstract

PROBLEM TO BE SOLVED: To provide a pressure sensitive element in which thickness is made to be thin, manufacturing is facilitated, and no occurrence of failure resulting from an assembling error is allowed.

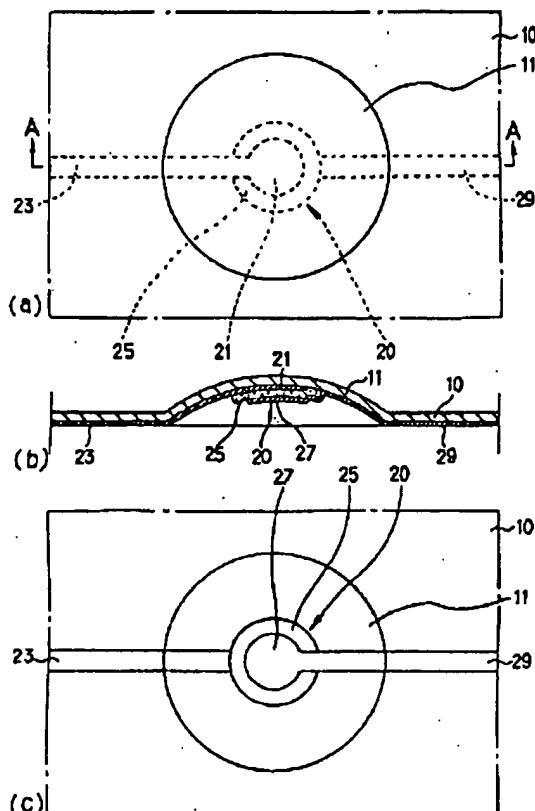
SOLUTION: A pressure sensitive element is composed of a pressure sensitive film element 20 formed in the center of the bottom face of the dome-like pushing portion 11 of a film 10. The pressure sensitive film element 20 is composed of an electrode pattern 21 formed on the face of the film 10, a pressure sensitive resistant film 25 formed on the electrode pattern 21, an electrode pattern 27 formed on a location opposite to the electrode pattern 21 on the pressure sensitive resistant film 25.

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25 感圧抵抗膜
41-4 導電パターン

31-5 基板(基材)

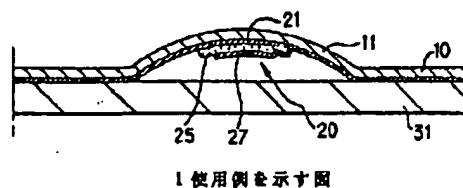
【図1】



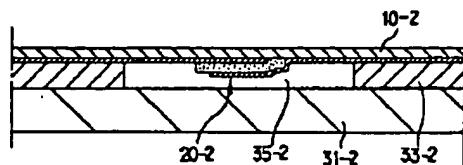
10 フィルム 20 感圧膜素子 21, 27 電極パターン 25 感圧抵抗膜

本発明の感圧素子を示す図

【図2】

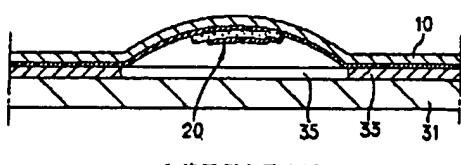


【図5】



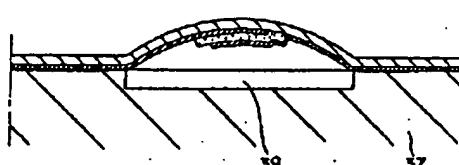
他の感圧素子の1使用例を示す図

【図3】



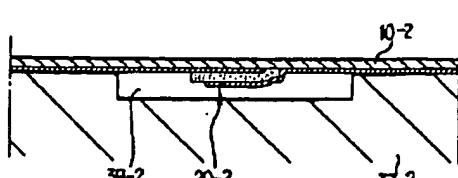
1 使用例を示す図

【図4】



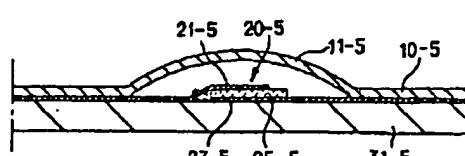
1 使用例を示す図

【図6】



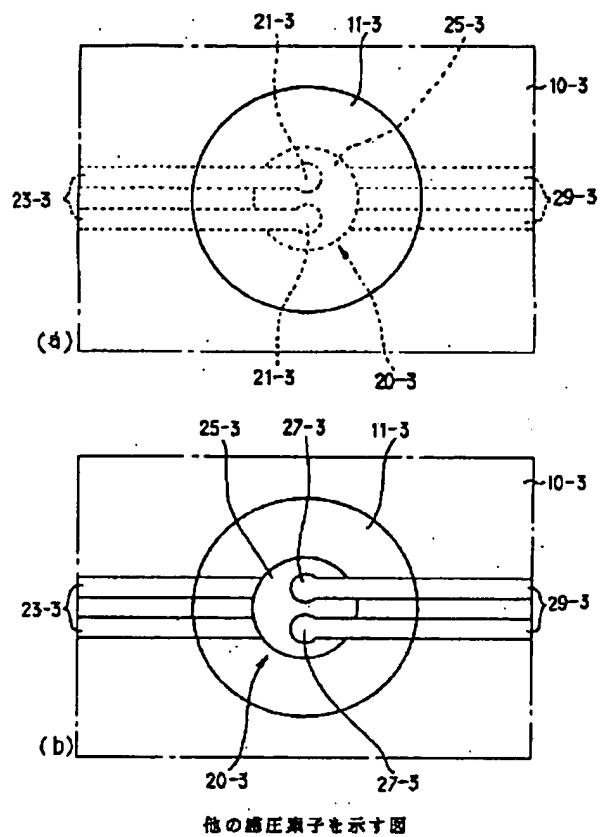
他の感圧素子の1使用例を示す図

【図9】

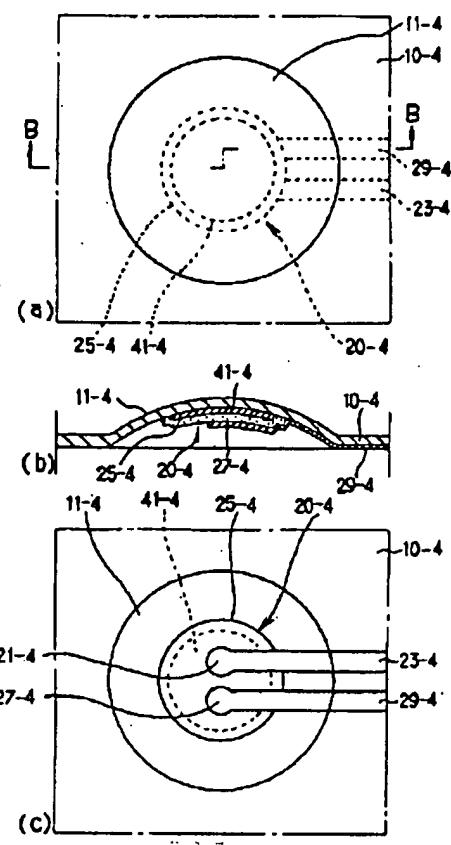


他の感圧素子を示す図

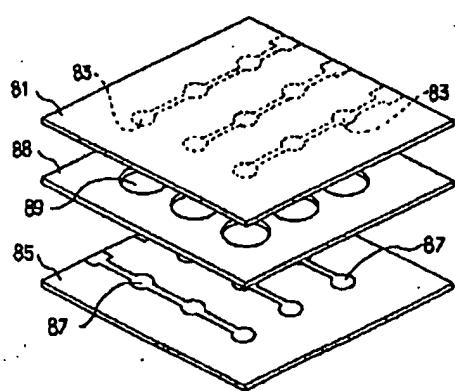
【図7】



【図8】



【図10】



【図11】

